

Electronically filed on March 6, 2009

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of:	Yoshihide SENZAKI	Confirmation No.:	3254
Serial No.:	10/524,980	Art Unit:	2823
Filed:	March 22, 2006	Examiner:	LEE, Hsien Ming
For:	<i>Low Temperature Deposition of Silicon Oxides and Oxynitrides</i>		
		Attorney Docket No.:	067538-5172-US

RESPONSE TO OFFICE ACTION

Mail Stop AMENDMENT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Commissioner:

In response to the Office Action dated January 6, 2009, please consider the following proposed amendments to the above-identified application and the remarks herein. Please amend the application as follows:

Amendments to the Claims begin on page 2 of this Amendment.

Remarks begin on page 6 of this Amendment.